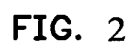


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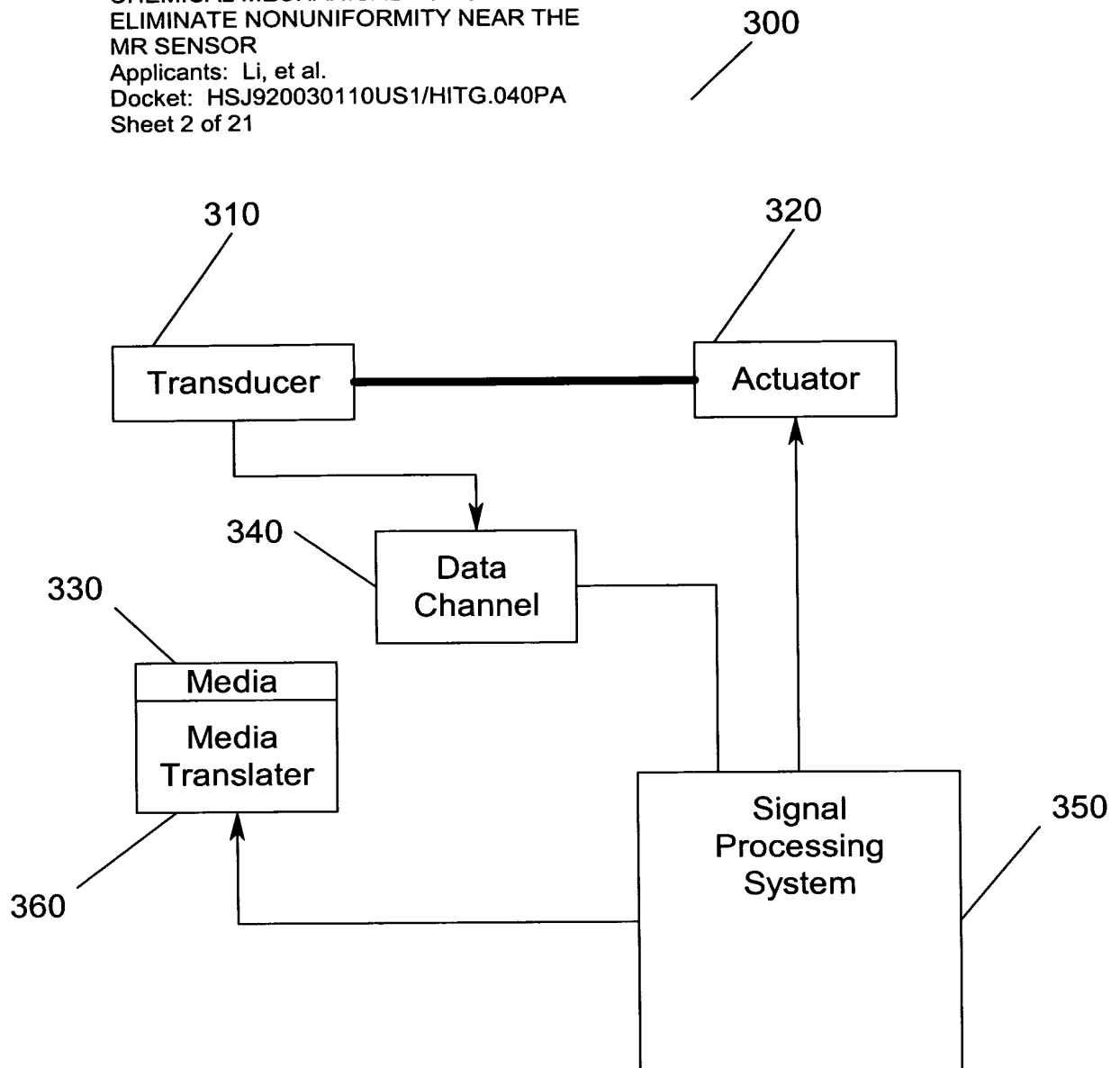


Fig. 3

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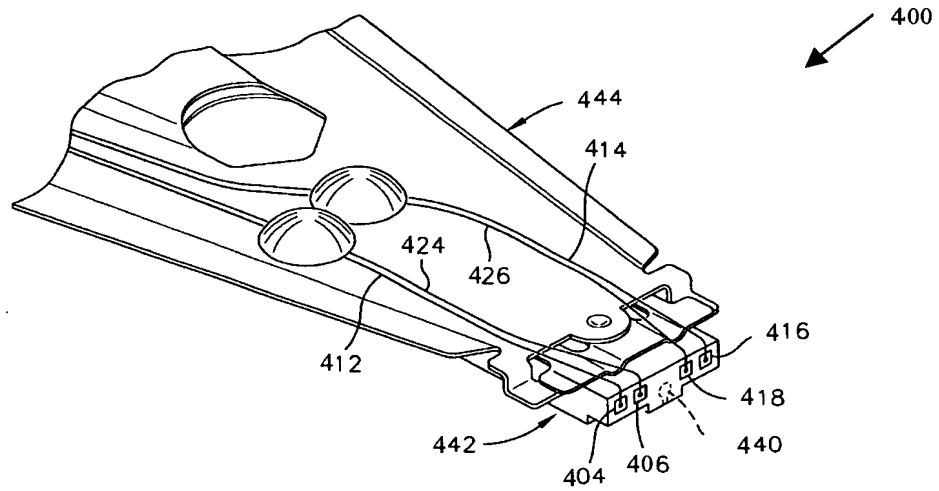
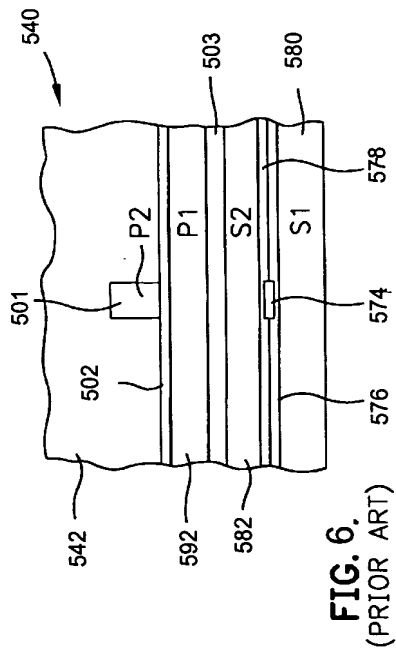
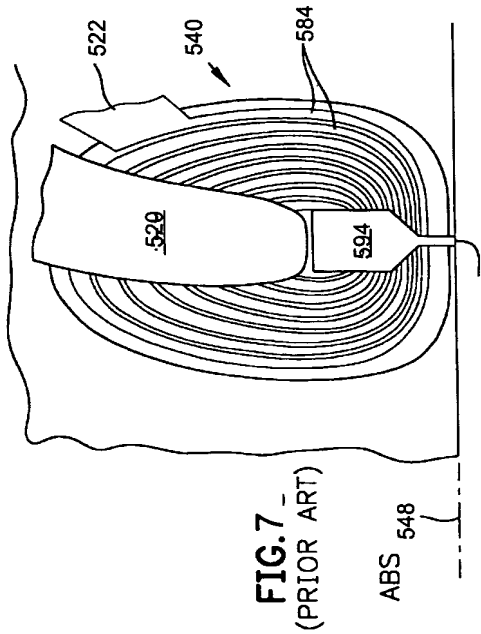
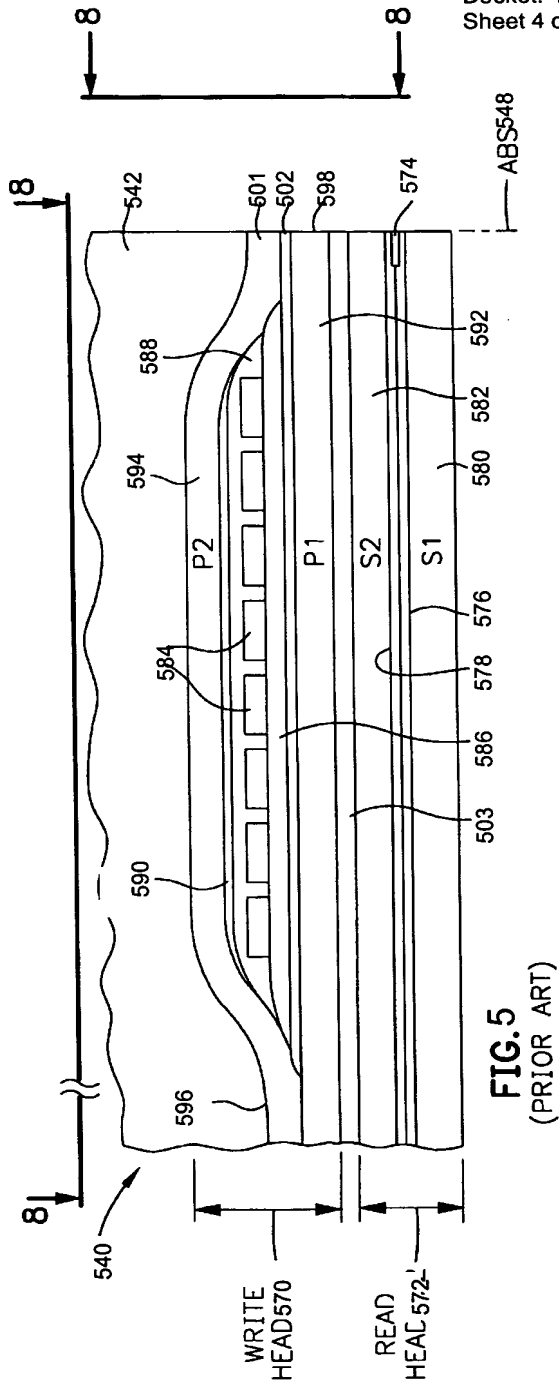


Fig. 4



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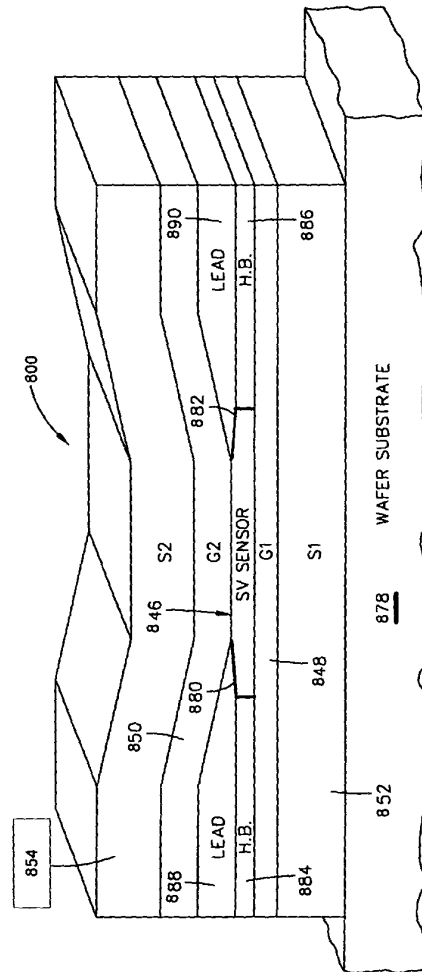


Fig. 8
(ABS)

Title: METHOD FOR FORMING A READ
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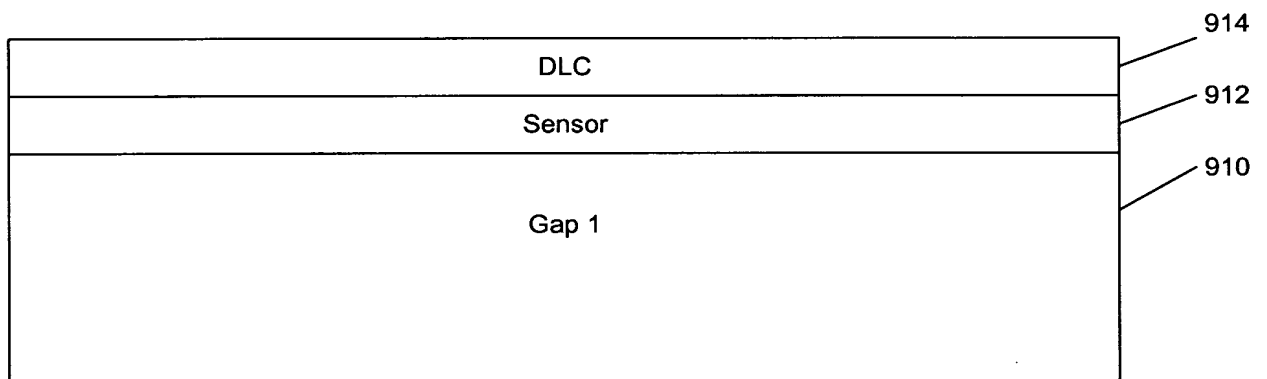


Fig. 9

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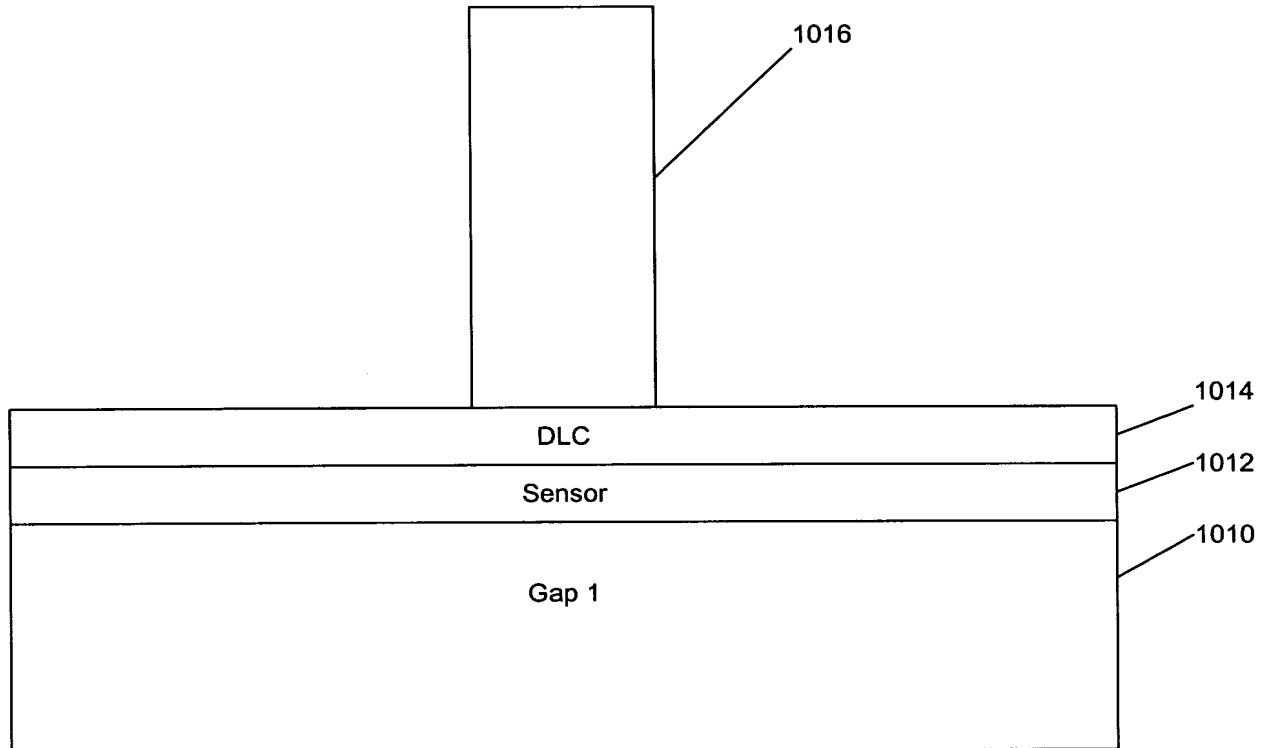


Fig. 10

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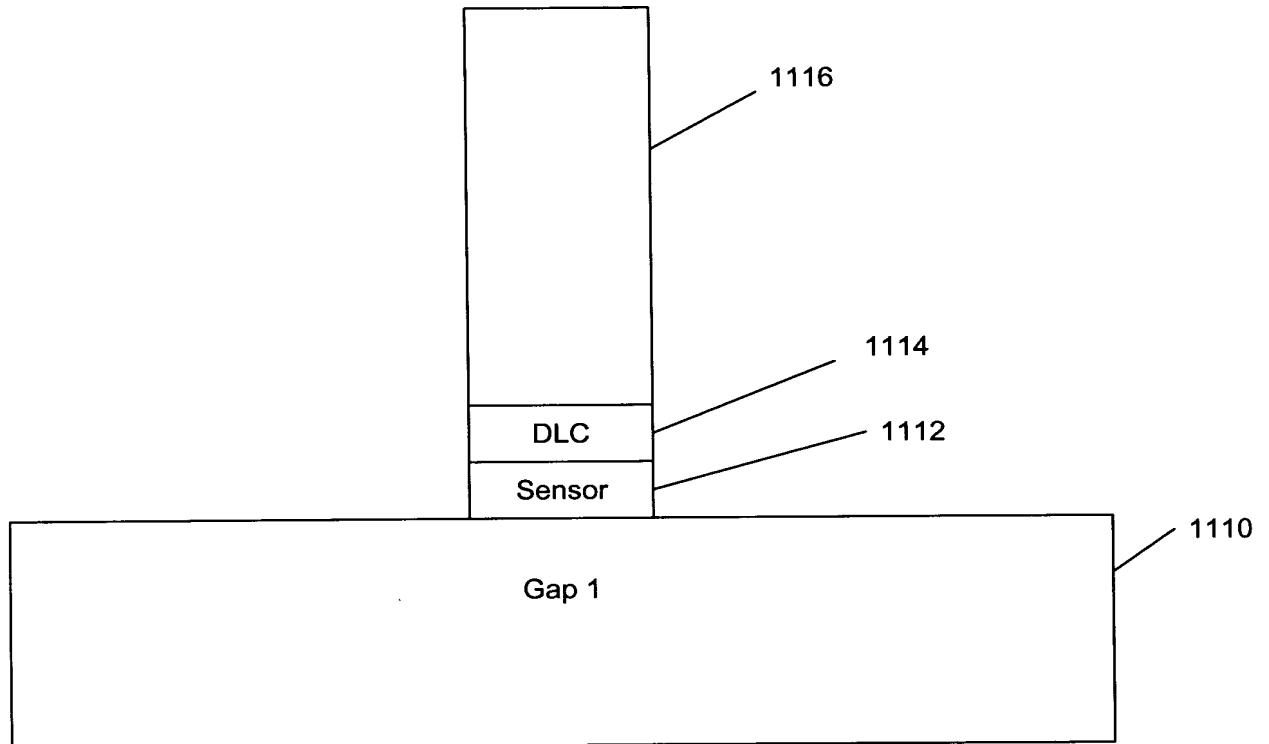


Fig. 11

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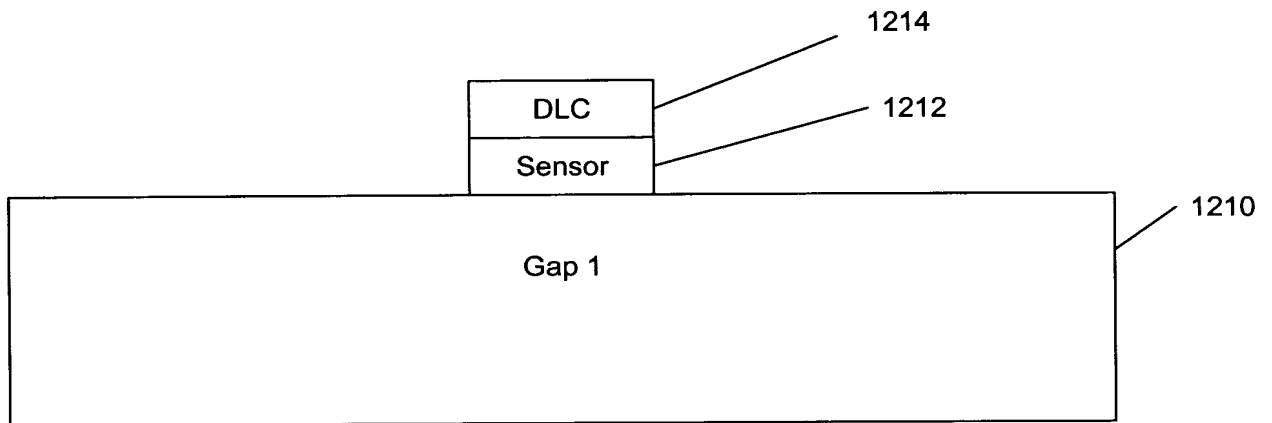


Fig. 12

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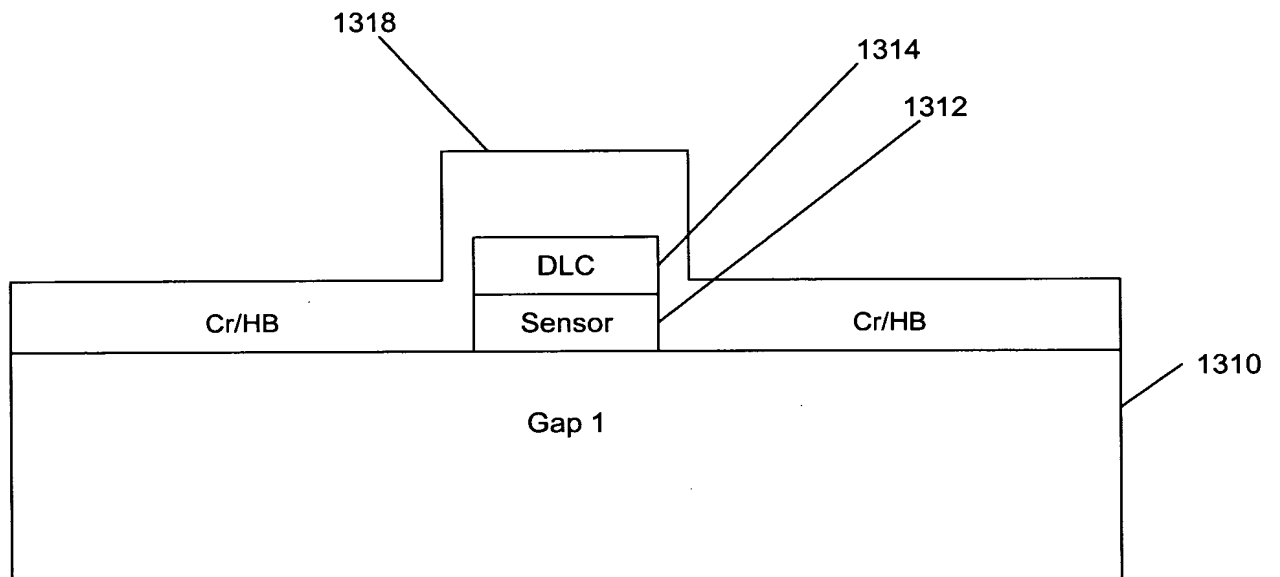


Fig. 13

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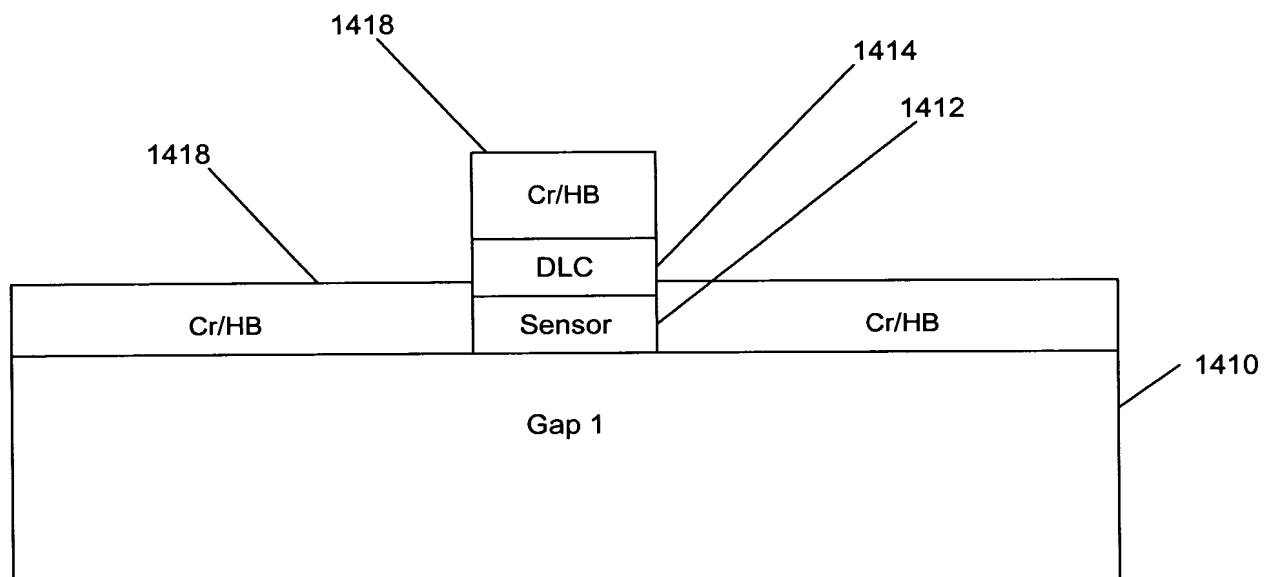


Fig. 14

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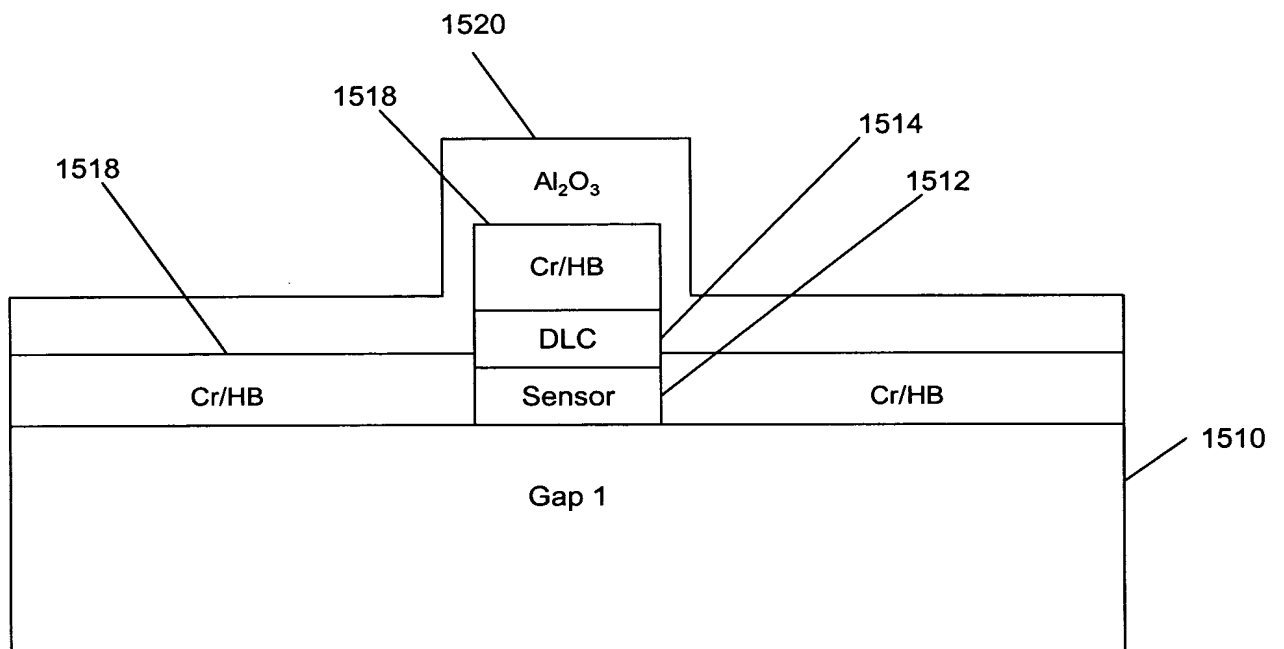


Fig. 15

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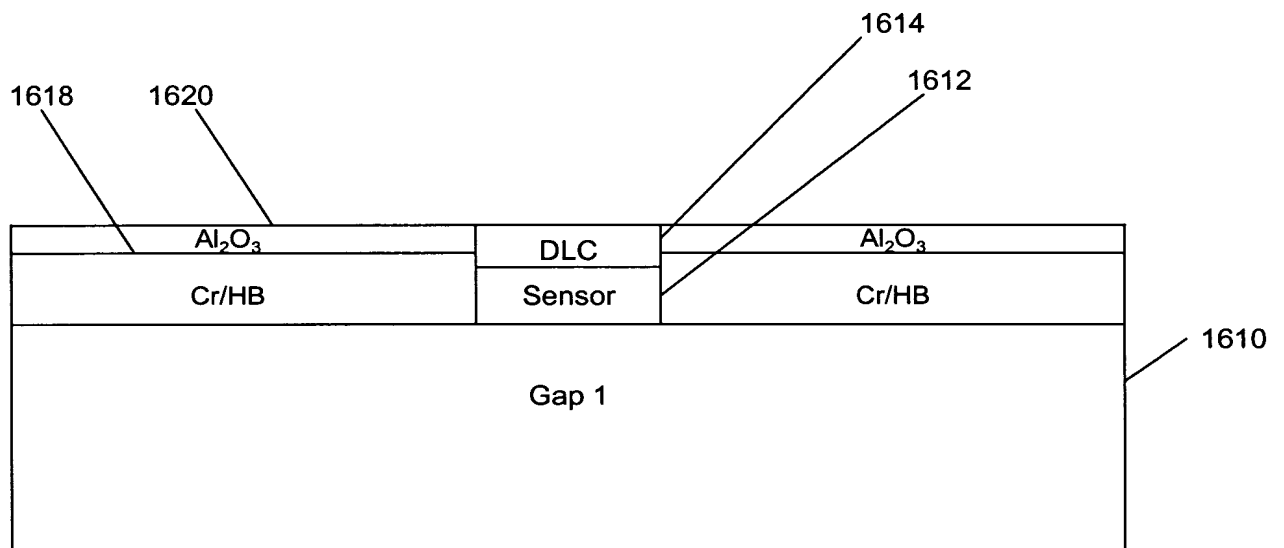


Fig. 16

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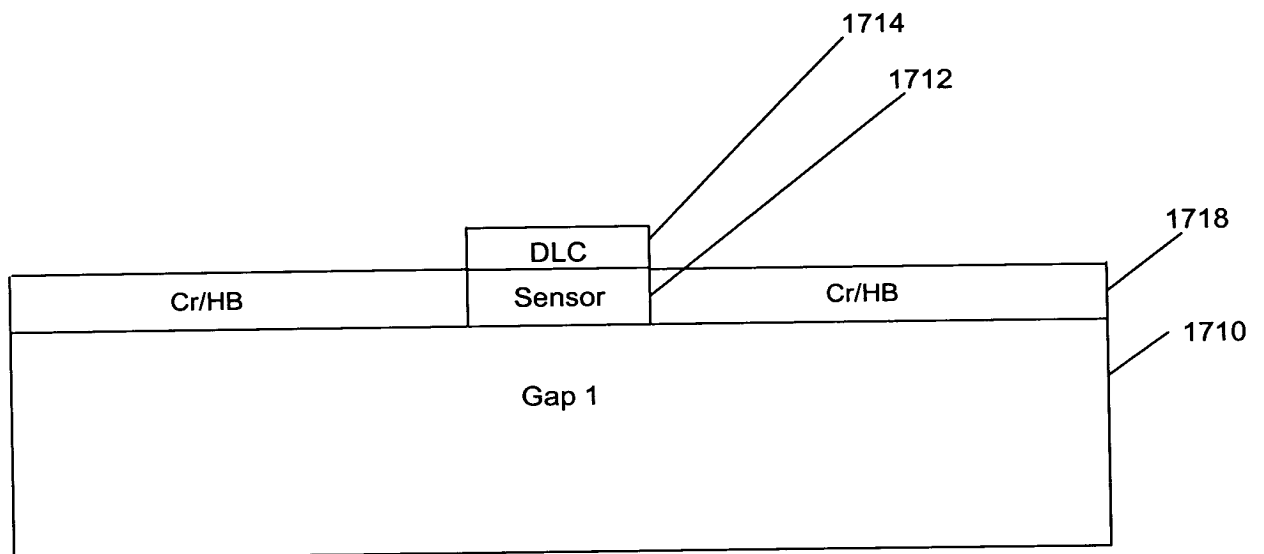


Fig. 17

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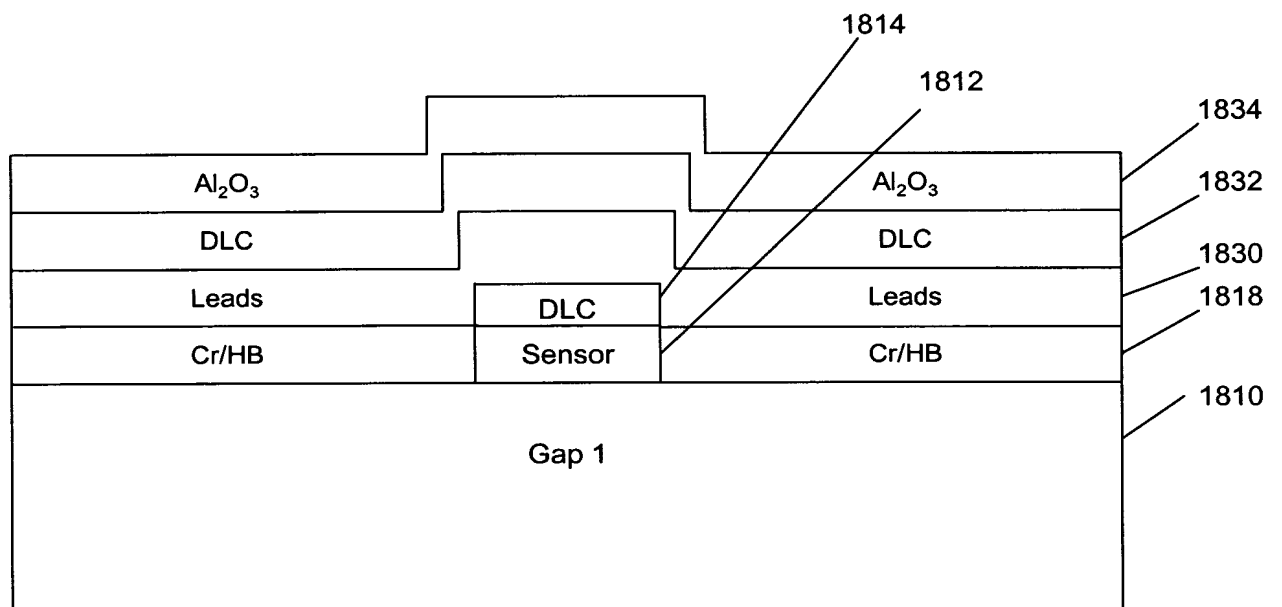


Fig. 18

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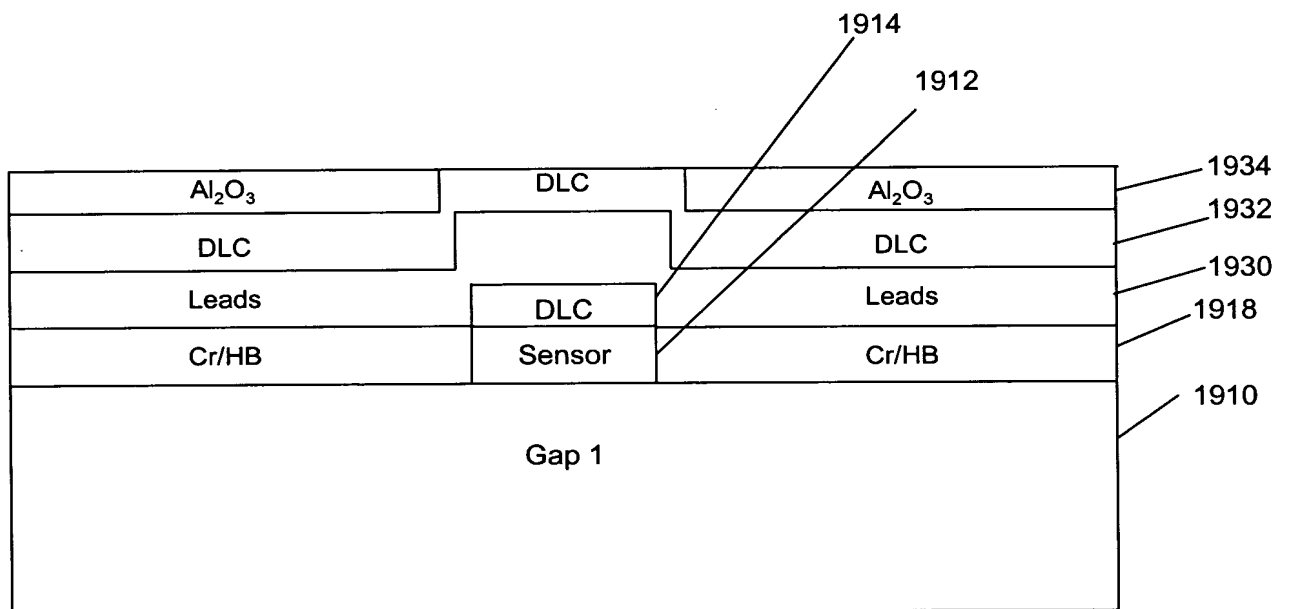


Fig. 19

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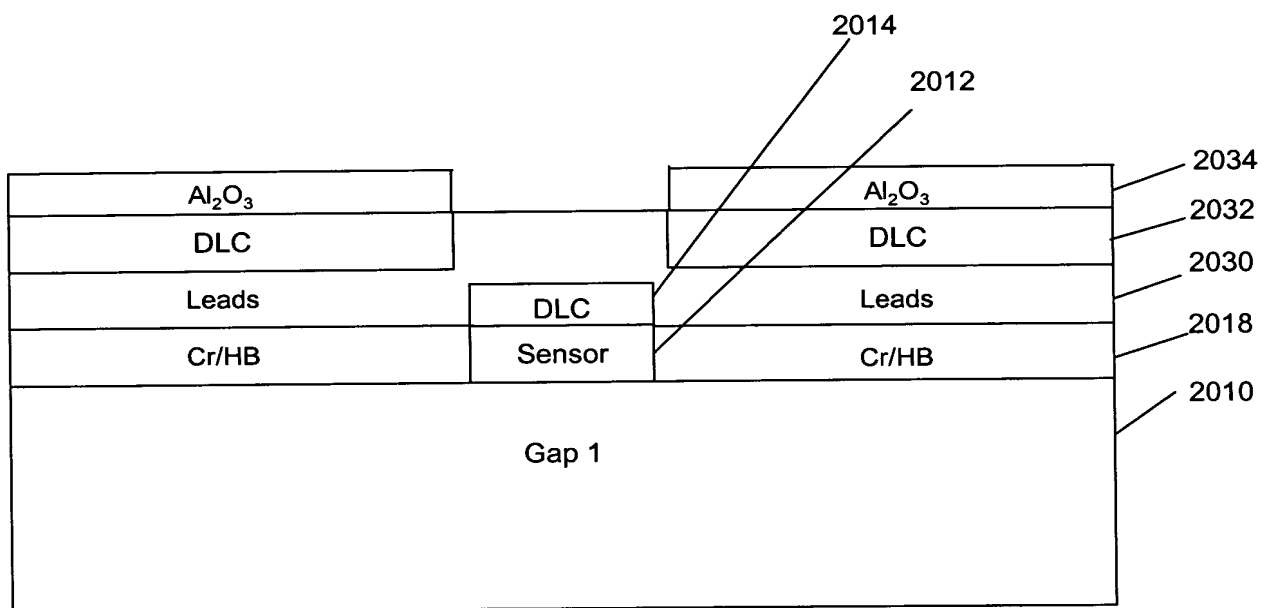


Fig. 20

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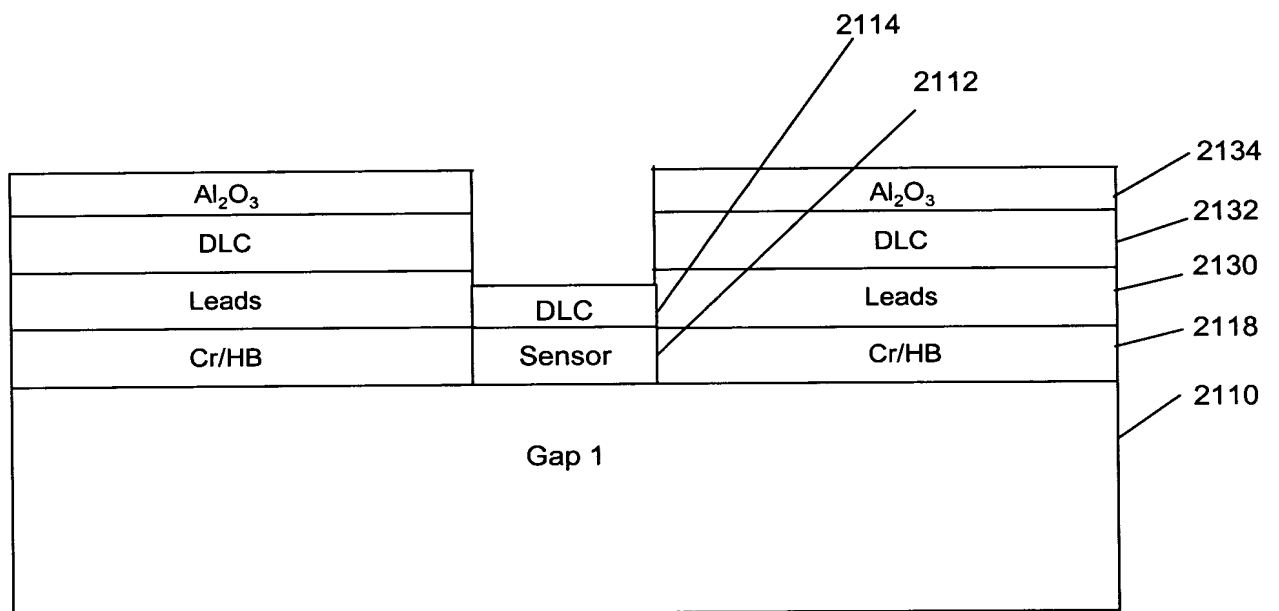


Fig. 21

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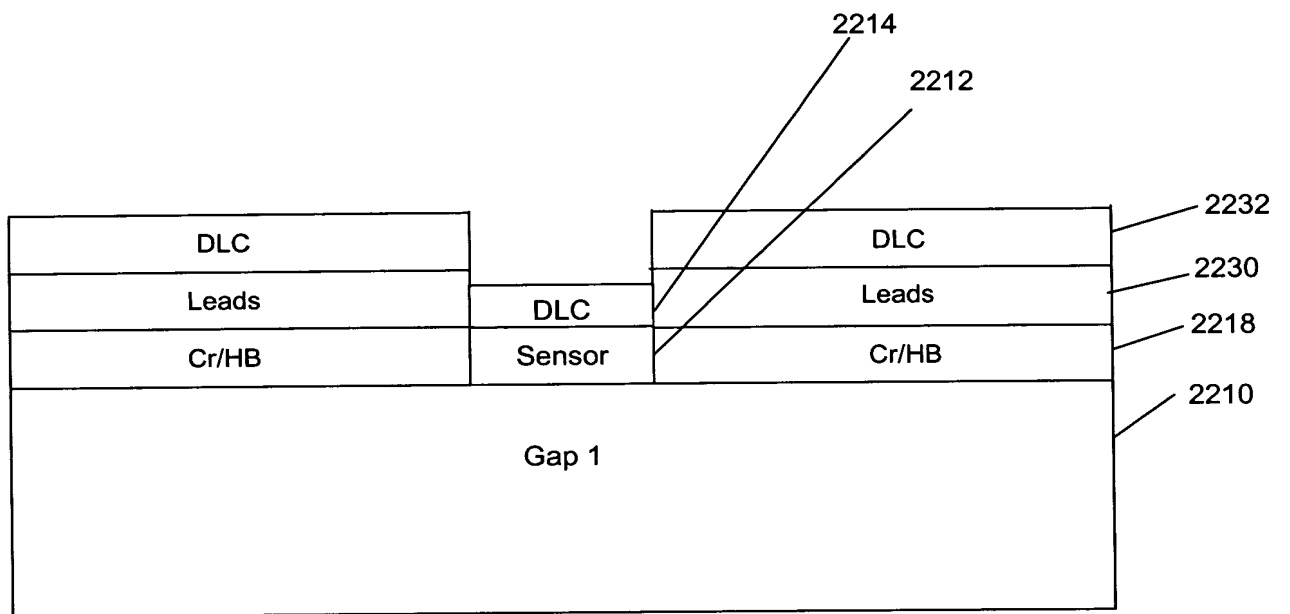


Fig. 22

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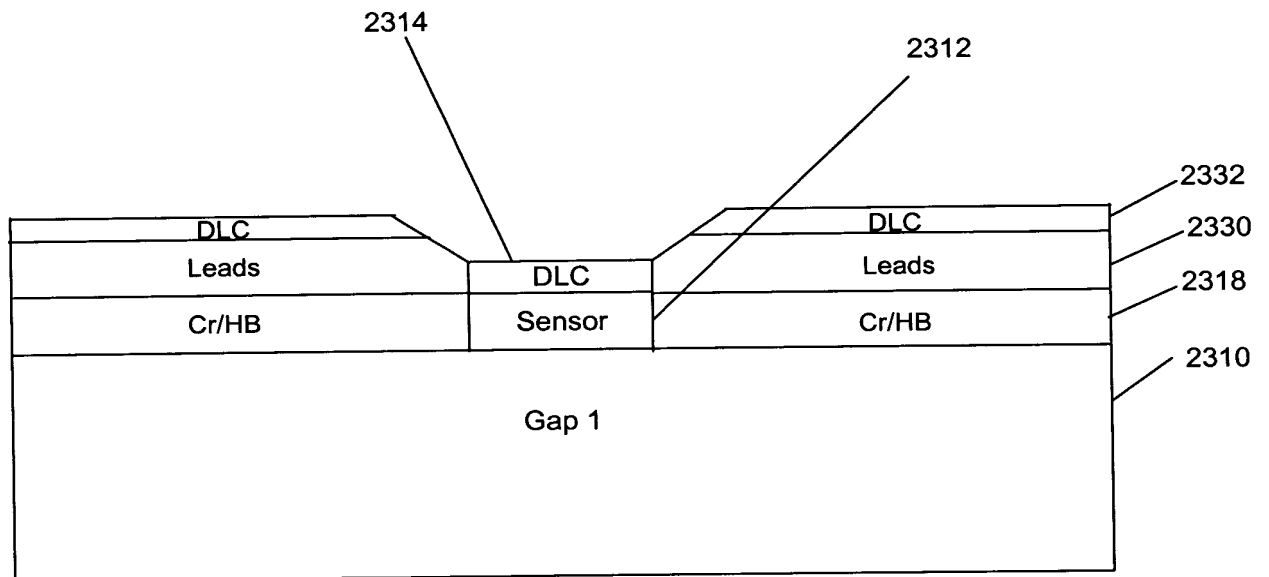


Fig. 23

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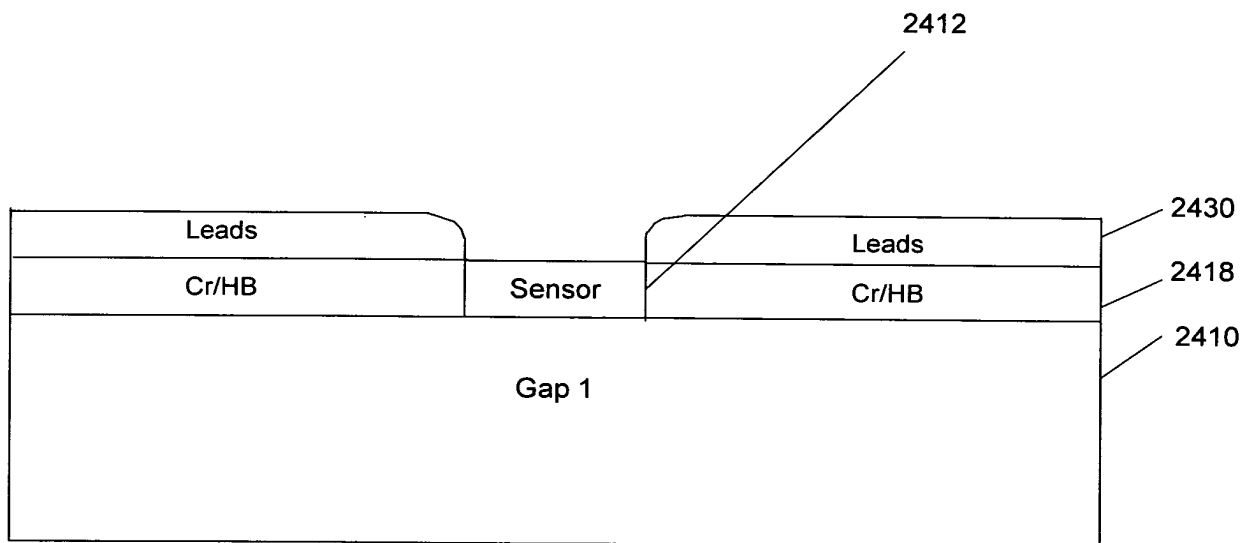


Fig. 24